

10/706624

Classification: 219/121.430

Examiner: PASCHALL, MARK

Inventor: SHIMIZU , AKIRA, et al

GAU: 3742

Status: 30 - DOCKETED NEW CASE - READY FOR EXAMINATION

Title: METHOD FOR SEMICONDUCTOR WAFER ETCHING

Bib Data report

Application Title:METHOD FOR SEMICONDUCTOR WAFER ETCHING

Application Num:  (in phx) 10706624 **Filing Date:**11/12/2003

Effective Filing:11/12/2003

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Examiner:61092 PASCHALL, MARK **Assignment Data:**) **Group Art Unit:**
3742 **Class/Subclass:** 219/121.430

State or Country:JAPAN **Sheets/Drawing:** 1 **Total Claims:**17
Independent Claims:3

▽ Inventors:

Last name, First name:	City:	Country or State:
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<u>NANBA, KUNITOSHI</u>	TOKYO	JAPAN

Attorneys: ALL **Attorney Docket No:**ASMJP.104DV1

Interference No: **Lost Case:**No **Unmatched Petition:**No **L&R Code:**1



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BIBDATASHEET

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Bib Data Sheet

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	RULE			

APPLICANTS

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** CONTINUING DATA *****

This application is a DIV of 10/068,092 02/05/2002 PAT 6,764,572

** FOREIGN APPLICATIONS *****

JAPAN 2001-056685 03/01/2001

IF REQUIRED, FOREIGN FILING LICENSE GRANTED

** 02/20/2004

Foreign Priority claimed	<input type="checkbox"/> yes <input checked="" type="checkbox"/> no	STATE OR COUNTRY	SHEETS	TOTAL	INDEPENDENT
35 USC 119 (a-d) conditions met	<input type="checkbox"/> yes <input checked="" type="checkbox"/> no <input type="checkbox"/> Met after Allowance	JAPAN	DRAWING 1	CLAIMS 17	CLAIMS 3
Verified and Acknowledged	Examiner's Signature _____ Initials _____				

ADDRESS

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TITLE

Method for semiconductor wafer etching

FILING FEE	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:	<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time)
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